

## Supporting information

# A Dual-Emission Fluorescence Sensor Based on TCPP@UiO-66-NH<sub>2</sub> for High-Sensitivity Detection of Copper Ions

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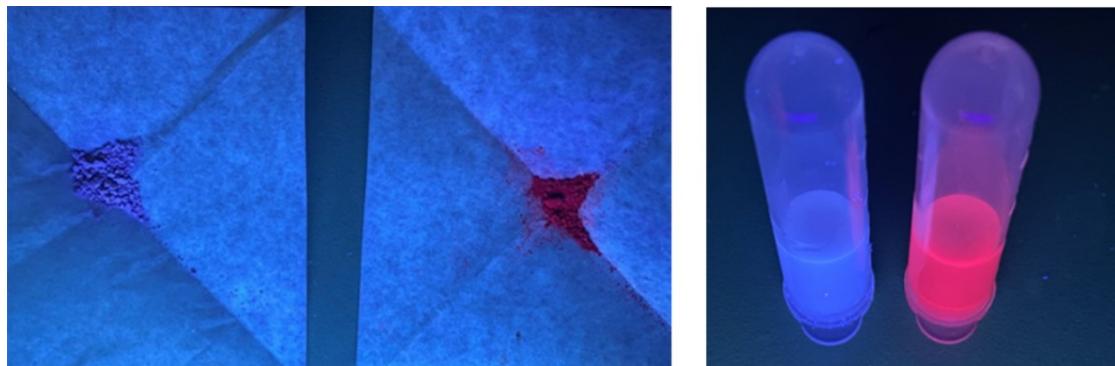
S2 XRD patterns of the (a) series TCPP@UiO-66-NH<sub>2</sub> and standard PCN-222. (b) Series TCPP@UiO-66-NH<sub>2</sub> fluorescence emission spectra and photographs ( $\lambda_{\text{ex}} = 300$  nm).

S3 TGA image of UiO-66-NH<sub>2</sub> and TCPP@UiO-66-NH<sub>2</sub> (in air).

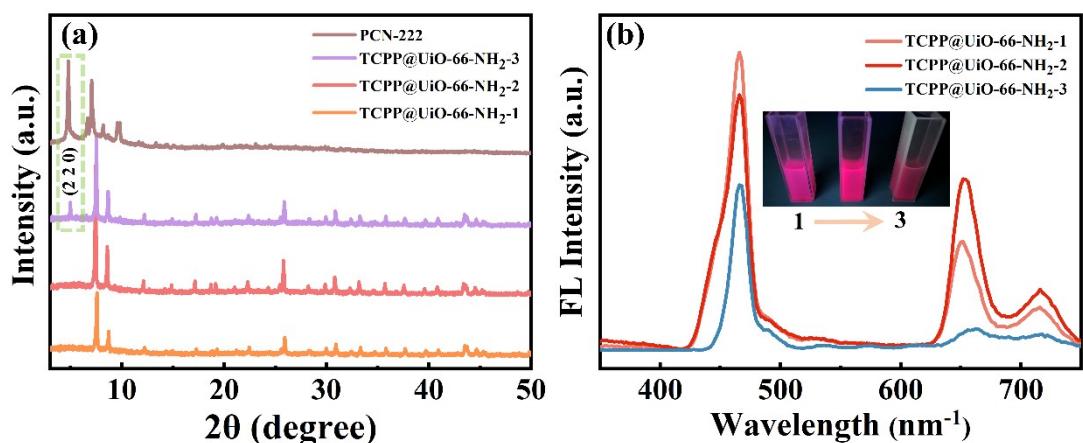
S4 The N<sub>2</sub> adsorption-desorption isotherm (a) and the pore size distribution (b) of UiO-66-NH<sub>2</sub> and TCPP@UiO-66-NH<sub>2</sub>.

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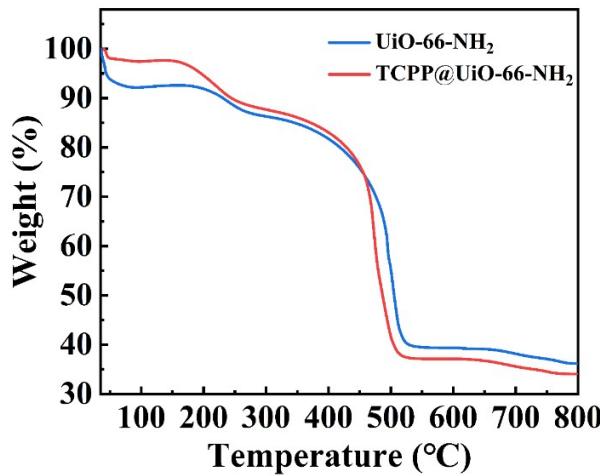
Table S1 Statistical data on the linear response range and detection limit of Cu<sup>2+</sup> based on fluorescent MOFs probes.



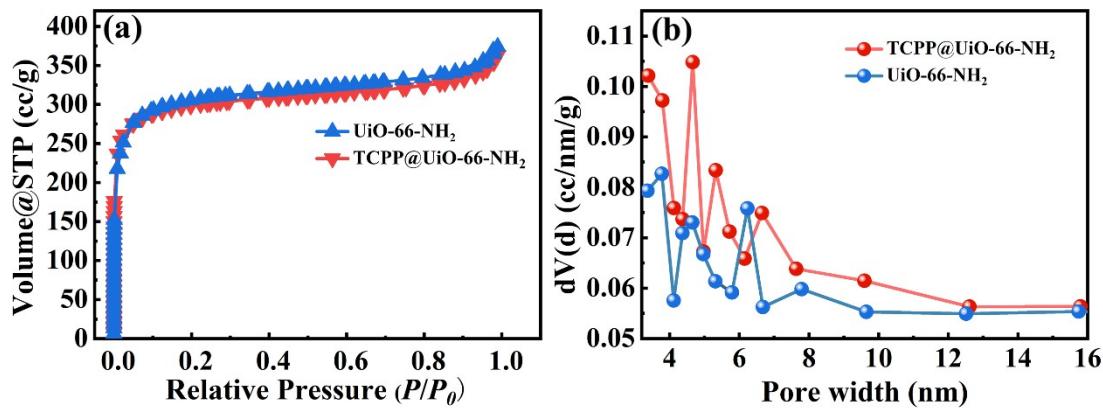
**Fig. S1.** The prepared samples (Left:  $\text{UiO-66-NH}_2$ , Right:  $\text{TCPP}@\text{UiO-66-NH}_2$ ) and their suspension liquids before and after TCPP doping. (photographs taken under UV-lamp, excited at 360 nm)



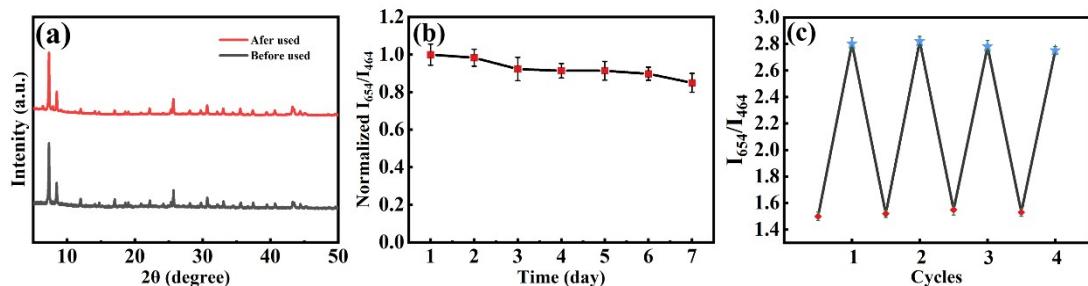
**Fig. S2.** XRD patterns of the (a) series  $\text{TCPP}@\text{UiO-66-NH}_2$  and standard PCN-222. (b) Series  $\text{TCPP}@\text{UiO-66-NH}_2$  fluorescence emission spectra and photographs ( $\lambda_{\text{ex}} = 300 \text{ nm}$ ).



**Fig. S3.** TGA image of  $\text{UiO-66-NH}_2$  and  $\text{TCPP}@\text{UiO-66-NH}_2$  (in air).



**Fig. S4.** The N<sub>2</sub> adsorption-desorption isotherm (a) and the pore size distribution (b) of  $\text{UiO-66-NH}_2$  and  $\text{TCPP}@\text{UiO-66-NH}_2$ .



**Fig. S5.** (a) The XRD of  $\text{TCPP}@\text{UiO-66-NH}_2$  before and after application. (b) Line chart of  $I_{466}/I_{654}$  ratio changes in  $\text{TCPP}@\text{UiO-66-NH}_2$  probe solution during 7 days. (c) Line chart of  $I_{466}/I_{654}$  ratio changes cycled four times  $\text{TCPP}@\text{UiO-66-NH}_2$ .

**Table S1** Statistical data on the linear response range and detection limit of Cu<sup>2+</sup> based on fluorescent MOFs probes.

| MOF   | Linear range<br>(μM) | LOD      | Ref.         |
|---|----------------------|----------|--------------|
| PCN-222-Pd(II)  | 0-2                  | 50 nM    | <sup>1</sup> |
| MIL-53-L  | 0-400                | 10 μM    | <sup>2</sup> |
| {[Nd <sub>2</sub> (NH <sub>2</sub> -BDC) <sub>3</sub> (DMF) <sub>4</sub> ] <sub>n</sub> } | 0-10 <sup>4</sup>    | 24.95 μM | <sup>3</sup> |
| Cd-MOF-74   | 0-5950               | 0.037 mM | <sup>4</sup> |
| MOF-525   | 0-20                 | 67 nM    | <sup>5</sup> |
| Eu <sup>3+</sup> @CAU-11  | 50-10 <sup>4</sup>   | 6.2 μM   | <sup>6</sup> |
| CDs-PCN-224   | 0-10                 | 44 nM    | <sup>7</sup> |
| TCPP@UiO-66-NH <sub>2</sub>   | 0-10                 | 24 nM    | This work    |

## References

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